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Substitute for form 1449B/PTO

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary) Sheet 2 of 4	Application Number	Not Assigned
	Filing Date	31 October 2003
	First Named Inventor	BINTORO, Jemmy
	Group Art Unit	Not Assigned
	Examiner Name	Not Assigned
	Attorney Docket Number	GTRC132

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or county where published.	T ³
LD		S. BOHM et al., A micromachined silicon valve driven by a miniature bi-stable electro-magnetic actuator, Sensors and Actuators 80 (2000) 77-83	
		YASUHIKO SHINOZAWA et al., A Proportional Microvalve Using a Bi-Stable Magnetic Actuator	
		MIRCEA CAPANU et al., Design, Fabrication, and Testing of a Bistable Electromagnetically Actuated Microvalve, Journal of Microelectromechanical Systems, Vol. 9, No. 2, June 2000	
		A. MECKES et al., Microfluidic system for the integration and cyclic operation of gas sensors, Sensors and Actuators 76 (1999) 478-483	
		HYOUNG J. CHO et al., A Bidirectional Magnetic Microactuator Using Electroplated Permanent Magnet Arrays, Journal of Microelectromechanical Systems, Vol. 11, No. 1, February 2002	
		T. LISEC et al., Thermally Driven Microvalve with Buckling Behavior for Pneumatic Applications, Sensors and Materials, Vol. 8, No. 5 (1996)	
		EDWIN T. CARLEN et al., Surface Micromachined Paraffin-Actuated Microvalve, Journal of Microelectromechanical Systems, Vol. 11, No. 5, October 2002	
		I. CHAKRABORTY et al., MEMS micro-valve for space applications, Sensors and Actuators 83 (2000) 188-193	
		DAVID S. ROBERTS et al., A Piezoelectric Microvalve for Compact High-Frequency, High-Differential Pressure Hydraulic Micropumping Systems, Journal of Microelectromechanical Systems, Vol. 12, No. 1, February 2003	
		PH. DUBOIS et al., Electrostatically Actuated Gas Microvalve based on a Ta-Si-N Membrane	

Examiner Signature	DONOVAN	Date Considered	05-15-03
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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LD		M. KOHL et al., Development of stress-optimised shape memory microvalves, Sensors and Actuators 72 (1999) 243-250	
		J. HAJI-BABAEI et al., Integrable Active Microvalve with Surface Micromachined Curled-Up Actuator	
		NELSIMAR VANDELLI et al., Development of a MEMS Microvalve Array for Fluid Flow Control, Journal of Microelectromechanical Systems, Vol. 7, No. 4, December 1998	
		LEVENT YOBAS et al., A Novel Bulk-Micromachined Electrostatic Microvalve with a Curved-Compliant Structure Applicable for a Pneumatic Tactile Display	
		CHARLES GROSJEAN et al., A Practical Thermopneumatic Valve	
		W.K. SCHOMBURG et al., Design optimization of bistable microdiaphragm valves, Sensors and Actuators A 64 (1998) 259-264	
		COLLIN A. RICH et al., A High-Flow Thermopneumatic Microvalve With Improved Efficiency and Integrated State Sensing, Journal of Microelectromechanical Systems, Vol. 12, No. 2, April 2003	
		S. MESSNER et al., A Normally-Closed, Bimetallically Actuated 3-Way Microvalve for Pneumatic Applications	
		ANTONIO BALDI et al., A Hydrogel-Actuated Smart Microvalve with a Porous Diffusion Barrier Back-Plate for Active Flow Control	
LD		ROBIN H. LIU et al., Fabrication and Characterization of Hydrogel-Based Microvalves, Journal of Microelectromechanical Systems, Vol. 11, No. 1, February 2002	

Examiner Signature	DONOVAN	Date Considered	09-18-05
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FEB 27 2004

Sheet

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LD		JEMMY SUTANTO BINTORO et al., Mechanical and Magnetic Analysis of a Latching Electromagnetic Microvalve	
LD		JEMMY SUTANTO BINTORO et al., Fabrication of a Bistable Electromagnetic Actuator for Microvalve	
LD		JEMMY SUTANTO BINTORO et al., A Bistable Electromagnetic Actuated Microvalve with Integrated Switching Mechanism	
LD		JEMMY SUTANTO BINTORO et al., A Structure of Bistable Electromagnetic Actuated Microvalve Fabricated on a Single Wafer, Implementing the SLA and PDMS Technique	

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